

"An extension of your own lab capabilities"

nanoUtah '15

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Ian R. Harvey, Associate Director



1967: Frank Wanlass (General Instruments - SLC)



Wanlass's patent portrayed an integrated CMOS inverter.

1969: Willem Kolff establishes first thin film capability supporting artificial organ research

1976-2001: HEDCO Microelectronics Laboratory: General Instruments tool donation

2001-2011: Utah Microfab focusing on implantable devices, MEMS and microelectronics

2004-2011: Surface Analysis & nano Imaging Lab (add XPS, SEM, FIB, AFM, Ellipsometry, Zygo)

2012-present: Transition to Utah Nanofab: ISO 4,5,6 (with ISO 5, BSL-2 bio bay), add new PECVD stack, 2nd DRIE, w/d ox, sub-micron litho, RTP

2012-present: Micron Microscopy Suite: 5,300 ft² adds FIB, TEM fast mapping tomo...



Increasing Cleanroom Capability Awesomeness

Cleanroom



thin film patterning • microfluidics laser & wire EDM μmachining • microsystems packaging







Surface Analysis & Correlative multi-scale analytical microscopy



Center for Engineering Innovation

sensors • actuators • system prototypes • advanced packaging

We supply critical...

...infrastructure



...tools and instruments..expertise





to support R&D success.









How Staff Interact...

- Train students to do their own work
- Provide analysis services and data interpretation
- High technical trust and interaction justify co-authorship



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Nanofab access cost kept low by subsidy (VP-R, Dean COE, USTAR)

- 24/7 operation user facility
- On-line or mobile scheduling
- Real-time cost/burn-rate tracking
- Low per-tool hourly rates (now the same across-the-state)
- Preliminary Data Seed Fund (3 months tool use reimbursed)
- Student projects funded (Ph-I full subsidy; Ph-II cost-shared)





Recent Equipment Additions

- Hi-resolution S/TEM
 - Ultrafast EDS for 2D mapping with hi-res imaging
 - 3D tomographic mapping
- LPCVD furnaces
- Heidelberg sub-µm mask making tool (900nm direct write)
- Wet/dry oxidation (lesson on don't buy based on price tag alone)— Loss of solid source doping capability
- Rapid thermal annealing (ETA Oct/Nov)
- Chilled finger for parylene (no more LN₂!!)
- Keyence 3D measuring microscope



Tool Roadmap

- Advanced Reactive Sputtering tool (USTAR-pending)
- Toxic materials sputtering (VO2, other)
- Si DRIE / poly etch
- Metal etcher
- Glass DRIE
- EV 620 advanced lithography tool
- Metal ALD
- PECVD
- Nanoscribe (nano 3DP)
- EELS
- EBL

Selected to host UGIM '16

world conference of peer research cleanroom adminstrators





Devener, Dr. Randy Polson, or Dr. Paulo Perez.

Equipment Request Form

Proposal Writing Support

Click here for the Preliminary Data Seed Fund

Click here for Nanofab Equipment List

Click here for images and descriptions of specific fab tools

Click here for images of the building, surface lab instruments, some representative research images

How to cite the lab in your publications

Lab Description

Also see <u>"Overview" page</u>

Utah's micro and nano science and engineering laboratories are interdisciplinary facilities supporting innovative transfer. Located at the University of Utah, these multi-purpose facilities provide the clean environment, exper micromachining, microfabrication, and nano-scale semi-conductor materials& device research.

The teaching laboratories strengthen undergraduate microfabrication curricula and train graduate students fror in the fundamentals of micromachining, microsystems design and characterization, microsensors and actuator

Premise: Our ability to create new sensory, actuation and control micro devices is severely restricted if we limit ourselves to design tricks and scaling effects.

→ We have to be able to add to that NEW MATERIALS. OSS-CONTAMINATION OSS-CONTAMINATION

DESK TOP PRO

DENTON VACUUM

Desktop Pro control cabinet with:

- DC power supply
- RF Power supply
- 2 Cathodes
- MFC

PZT.

- »disposable » Pumps
- Replaceable chamber

